

EDC 650 SERIES

Complete Process Control



Proven

Over 12,000 systems installed worldwide. Laurell Technologies exclusive "Dry In, Dry Out" process ensures the wafer and chemical delivery path are cleaned and dried after every use.

Flexible

Master Design with more actual processes and substrates supported than all others combined. Capable of in-situ mixing of process chemicals for ultimate flexibility.

Safe

Interlocks and electronic safety systems combined with the highest quality construction and material use ensure the operator is protected.



Our Expertise at Your Convenience

Laurell Technologies has 28 years of experience with our customers' complex processes, multiple chemistries, safety issues, waste containment, and disposal issues.

Benefit from our expertise and let us engineer your convenient solution.



WS-1000 Work Station

EDC-650-8NPP & EDC-650-8TFM

With Optional Touch Screen Interface

Options and Accessories

WS-1000 Wet Station: Custom designed and built by Laurell Technologies in-house

Touch Screen Interface: Control, program and monitor all operations with a touch

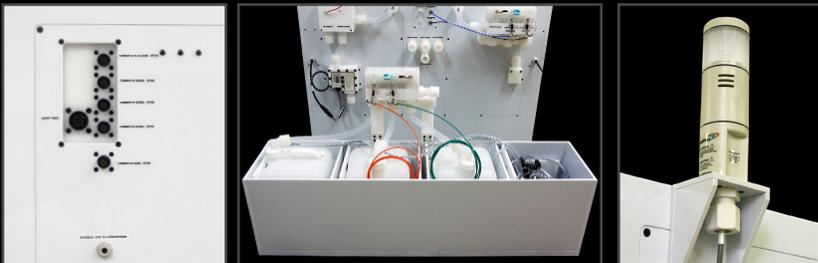
Rinse to Resistivity: Detects rinse completion and alerts the processor to dry the substrate, saving valuable resources usually wasted on a time-based system

Multi-Position Non-Contact Level Sensing: Either in a drain reservoir or supply container - fully programmable.

Leak Detection: Laurell uses the most dependable sensor technology available - audible and visual alarms with industry-standard light tree

Heated Process Chemistry: with point-of-use or recirculation type heat exchangers

Teflon® Housing: We only use **semiconductor grade Teflon®** with **zero porosity** to prevent "memory" effects when changing chemicals.



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